



70th ICFA Advanced Beam Dynamics Workshop
on High Luminosity Circular e+e- Colliders



中国科学院高能物理研究所
Institute of High Energy Physics
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CEPC
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CEPC Vacuum system development progress

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Content

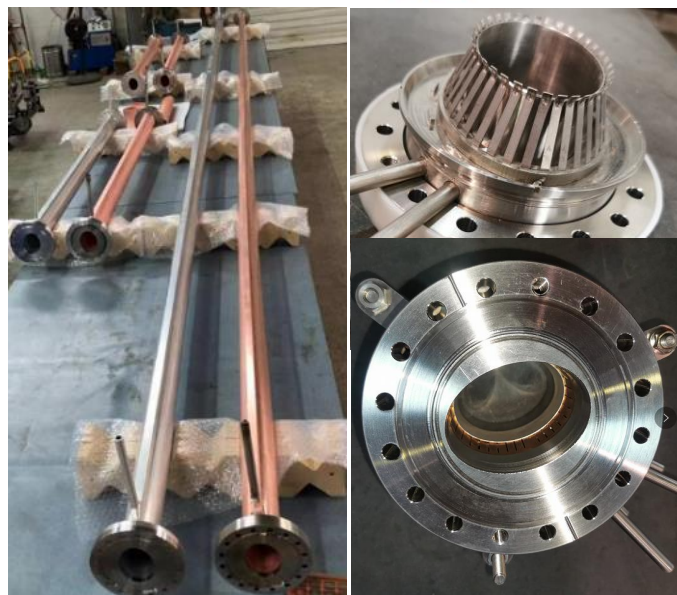
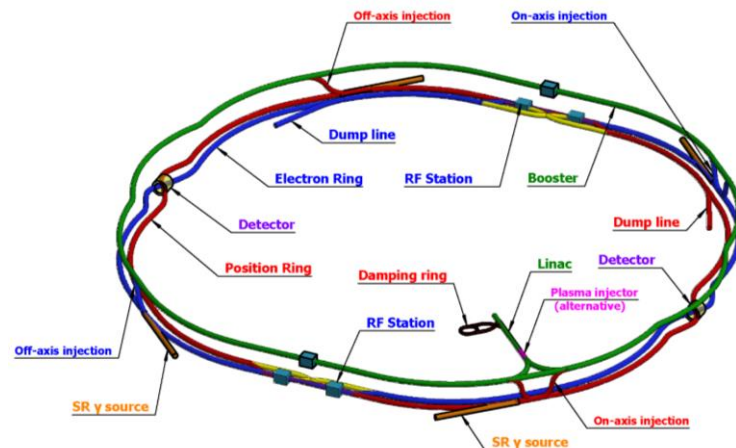
- Preview of CEPC vacuum system
- Collider rings, Booster ring, Linac Vacuum
- **Production line development of NEG coating/ Spray for heating film in EDR**
- **Components development in EDR**
- **Summary**

Preview of CEPC vacuum system

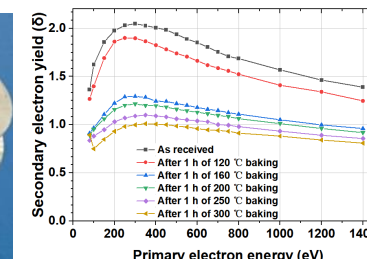
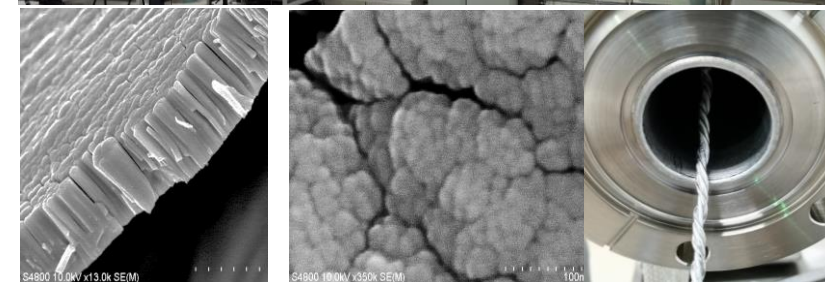
Machine and Vacuum Parameters

	E	I	ρ
	Gev	A	m
Higgs	120	0.0167	10700
W	80	0.084	10700
Z	45.5	0.803	10700
tt	180	0.0033	10700

Accelerator	length/m
LINAC	1,601+335
Damping ring	147
Booster	100,000
Collider	200,000
Transport line	4,680
<i>Total length/m</i>	<i>306,763</i>



◆ Technical developments in TDR



Those prototypes have a good application in HEPS.

Vacuum requirements and configuration

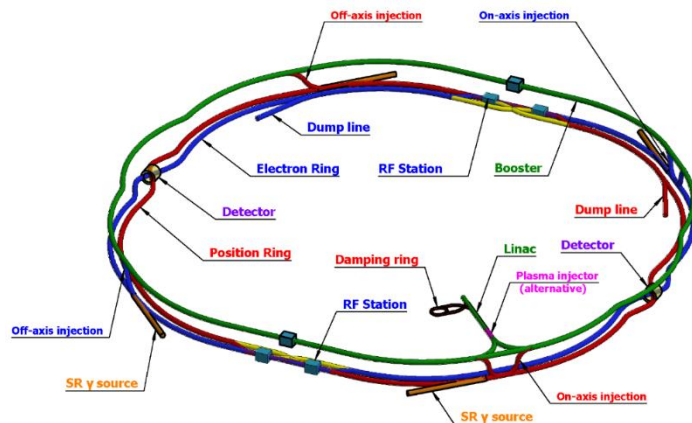


	Energy	Material	Cross Section/mm	Length/m	Dynamic pressure /Torr
LINAC	30 GeV	Stainless steel, copper	Φ20~30	1,601+ 335 (BTL)	Acc $<2 \times 10^{-7}$ E-gun $<2 \times 10^{-8}$
Damping ring	1.1 GeV	Extruded aluminum 6061	Φ30/Al 6061	147	$<2 \times 10^{-8}$
Booster	30 to 180 GeV	Extruded aluminum 6061	Φ56/thickness of 2mm	100,000	$<3 \times 10^{-8}$ tt $<4 \times 10^{-8}$
Collider	45.5~180 GeV	Extruded copper, NEG film SEY <1.2	Φ56/thickness of 2mm	100,000 × 2	Z $<8 \times 10^{-10}$ tt $<1 \times 10^{-8}$
MDI	45.5~180 GeV	Copper/tungsten alloy, NEG film	Φ20	12	$<3 \times 10^{-9}$
LTB	30 GeV	Stainless steel	Φ56	3,000	$<1 \times 10^{-7}$
BTC(CTB)	6 GeV	Stainless steel	Φ56	240 × 6	$<1 \times 10^{-7}$
DL	1.1 GeV	Stainless steel	Φ30	240	$<1 \times 10^{-7}$

Layout & configuration of Collider

	<i>Classification</i>	<i>length/m</i>
collider	Arc beam pipe	78752
	Straight section beam pipe	8456
	RF Substitute pipe	1192
	RF system	352
	Insertion and extraction	286
	Manifold for SIP	1333
	Bellows	2082
	BPM	300
	Manifold for Gauge & RGA	247
	Detector 1	12
	Detector 2	12
	Collider section	7000
	Total length	100000

Parameter	e ⁺ & e ⁻
Energy [GeV]	45.5~180
Beam current [A]	0.0033~1.39
Circumference [m]	100,000 × 2
Bending radius [m]	10,700
Beam pipe material	Extruded copper (water-cooled) NEG coating
Beam pipe shape (mm)	Φ56/thickness of 2mm
Pump type in arcs	SIP

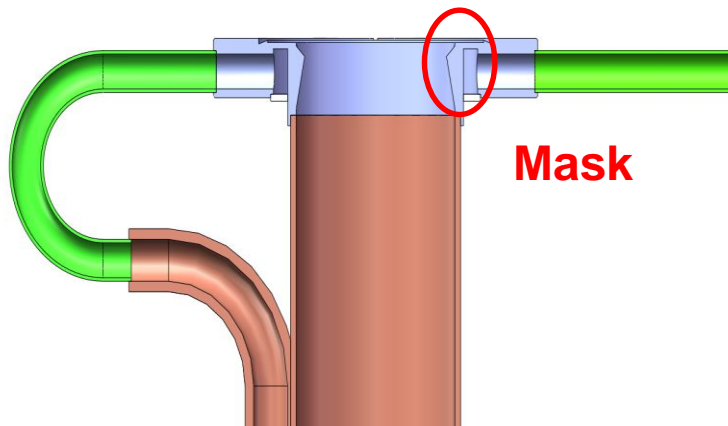


Modes	E (Gev)	Beam gas scattering lifetime (h)	Vacuum requirement (Torr)
Higgs	120	10	2×10^{-9}
W	80	5	1.5×10^{-9}
Z	45.5	3	8×10^{-10}
tt	180	15	1×10^{-8}

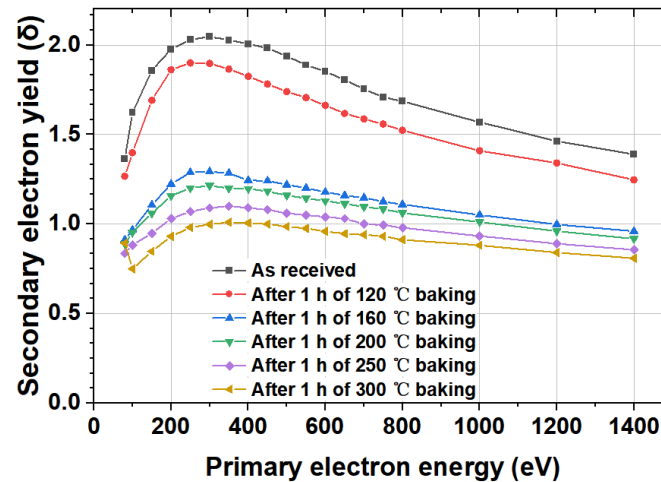
Collider rings Vacuum requirements and configuration



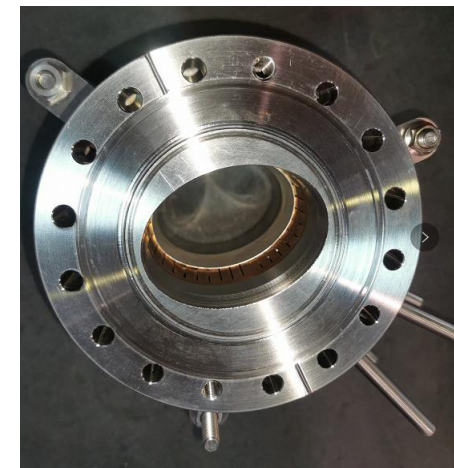
- Good beam lifetime must be achieved soon after the initial start-up with a stored beam.
- The vacuum system must be capable of quick recovery after sections are exposed to air for maintenance or repairs.
- The chamber wall must be as smooth as possible to minimize electromagnetic fields induced by the beam.
- NEG coating of 200nm is employed to suppress e-cloud of positron ring and absorb residual gases simultaneously. SEY will blow 1.2 after 24h activation of 180°C and could even lower under higher activation temperature.
- Similar to positron ring, NEG coating is proposed to vacuum chamber of electron storage ring to absorb extra gas load.



On-line mask



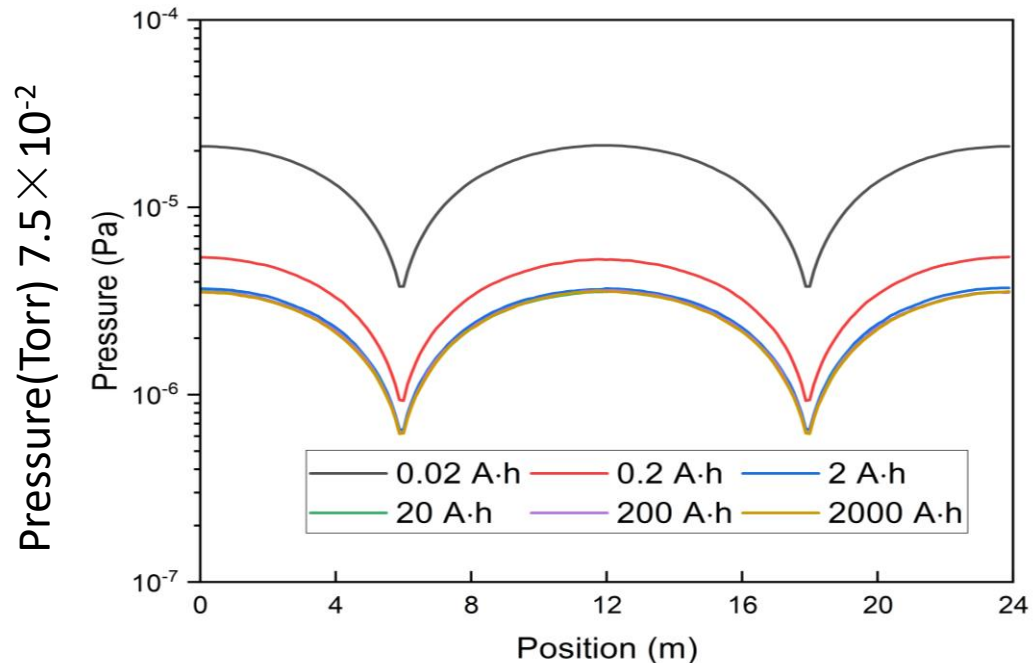
NEG coating



RF shielding bellows

Layout & configuration of Booster

- ◆ Booster will work in four modes of higgs, W, Z, tt under 30MW and 50MW alternatively. 50MW is given to calculate the vacuum parameters as it has the highest energy and gas load.
- ◆ The main pumping process will then be followed by ion pumps distributed around the circumference at intervals of about 12 m.



Parameter	e ⁺ & e ⁻
Energy [GeV]	30~180
Beam current [A]	0.11~14.4 × 10 ⁻³
Circumference [m]	100,000
Bending radius [m]	11,380.8
Beam pipe material	Extruded Al
Beam pipe shape (mm)	Φ56/thickness of 2mm
Pump type in arcs	SIP
Dynamic pressure /Torr	<3 × 10 ⁻⁸ tt<4 × 10 ⁻⁸

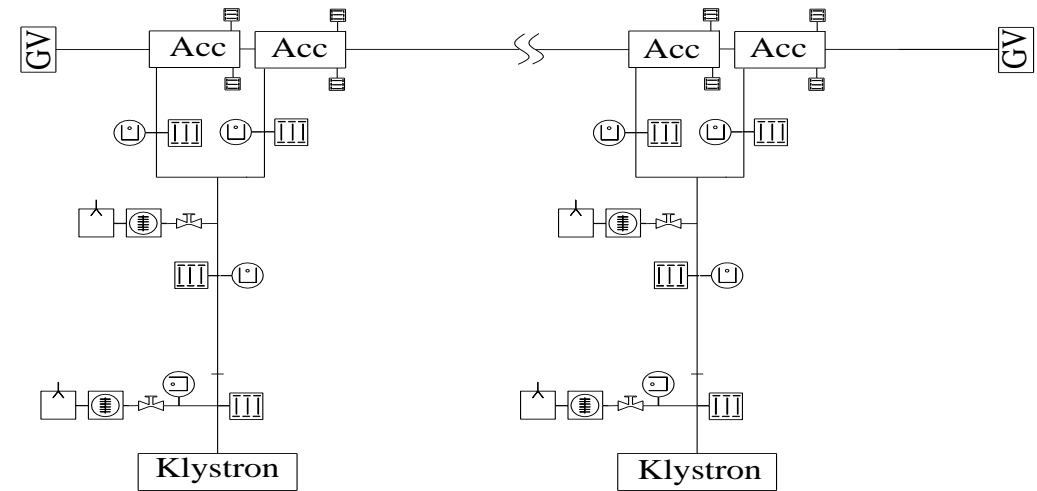
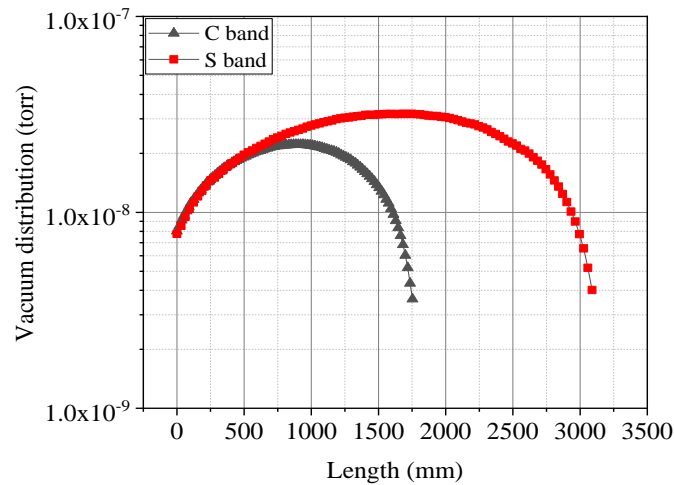
	Classification	length/m
booster	arc beam pipe	78428
	Straight section beam pipe	17010
	RF Substitute pipe	384
	RF system	96
	insertion and extraction	198
	Manifold for SIP	1250
	Bellows	850
	BPM	240
	Manifold for Gauge & RGA	1544
	total length	100000

Linac vacuum system

- ◆ The Linac vacuum system with a length of 1936m is divided into 59 sections. it consists of electron gun, bunching system, accelerating structures .
- ◆ Sputter ion pumps: 3431; Vacuum gauges: 1352; Gate valves: 60

Section	Static pressure /Torr	Dynamic pressure /Torr
E-gun	$<1 \times 10^{-9}$	$<2 \times 10^{-8}$
Buncher	$<5 \times 10^{-8}$	$<2 \times 10^{-7}$
Accelerating structure	$<5 \times 10^{-8}$	$<2 \times 10^{-7}$
Waveguide	$<5 \times 10^{-8}$	$<5 \times 10^{-7}$

◆ Most of the components are made of oxygen-free copper . The thermal outgassing rate is 1×10^{-11} Torr·l/s·cm².



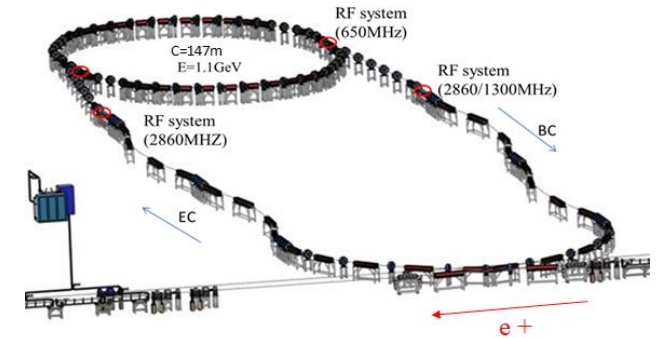
The static pressure distribution of a accelerator structure

Vacuum diagram of klystron and accelerator structures

Layout of Damping ring, Transport line

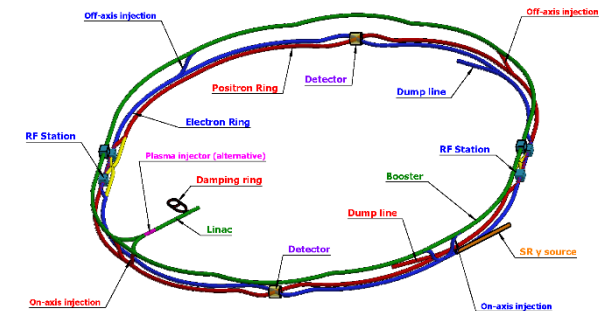
	Classification	length/m
DR	arc beam pipe	119.0
	Straight section beam pipe	14.0
	RF Substitute pipe	0.0
	RF system	3.0
	insertion and extraction	2.8
	Manifold for SIP	1.5
	Bellows	1.5
	BPM	4.0
	Manifold for Gauge & RGA	1.5
	total length	147.3

Parameter	e ⁺ & e ⁻
Energy [GeV]	1.1
Beam current [A]	0.012~0.024
Circumference [m]	147
Bending radius [m]	2.87
Beam pipe material	Extruded Al
Beam pipe shape (mm)	Φ30/thickness of 1
Pump type in arcs	SIP
Dynamic pressure /Torr	2 × 10 ⁻⁸



	Classification	length/m	Note
transport line	linac to booster	3000	e- & e+ 1500 m
	booster to colider	960	On axis: e- & e+ 240 m Off axis: e- & e+ 240 m
	colider to booster	480	e- & e+ 240 m
	damping ring	240	In & ex 120 m
	total length	4680	

Parameter	e ⁺ & e ⁻
Linac to Damping Ring	
Energy (GeV)	1.1 GeV
Linac to Booster	
Energy (GeV)	30 GeV
Booster to Collider	
Energy (GeV)	45 GeV~180 GeV
Dynamic Pressure (Torr)	2e-8



Damping ring vacuum system

- ◆ For the DR, with values of $E = 1.1$ GeV, $I = 0.012\sim 0.024$ A, and $\rho = 2.87$ m, these equations give a total synchrotron radiation power of $P_{SR} = 1.08$ kW and a linear power density of $P_L = 60.1$ W/m.

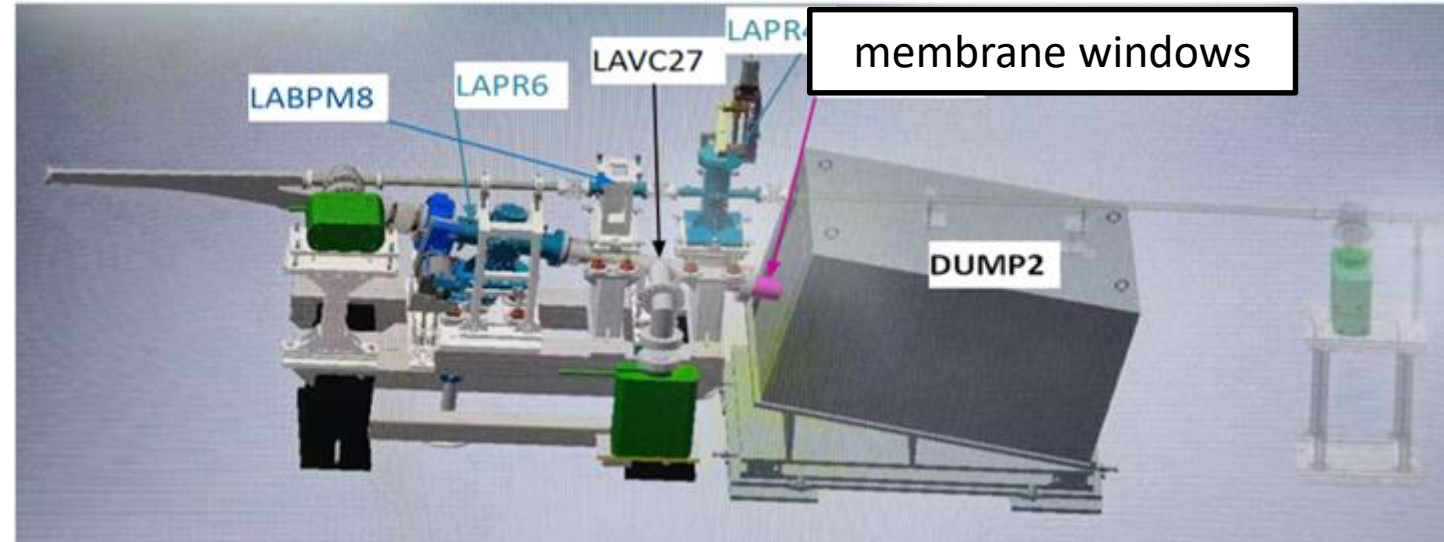
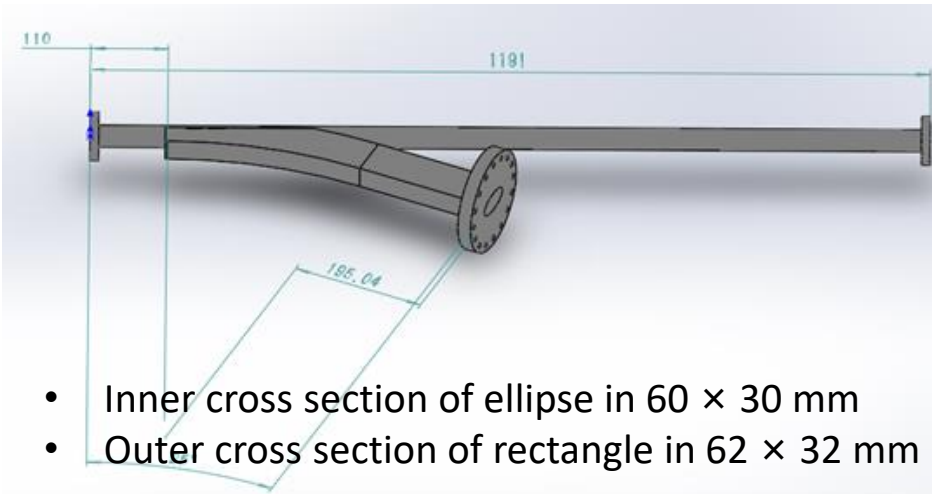
The gas load under different beam energy and beam density

Mode	E	I	PSD	P_L	Q_{gas}	Q_{LSR}	P_{ave}
	<i>GeV</i>	<i>A</i>	<i>Molecules/photon</i>	<i>W/m</i>	<i>Torr·L/s</i>	<i>Torr·L/s·m</i>	<i>Torr</i>
	1.1	0.024	2.00E-06	60.1	1.28E-06	7.09E-8	1.78E-08

- With an effective pumping speed of 15 L/s and a distribution of 2 meters sputtering ion pumps, the vacuum value of 1.78×10^{-8} Torr will be reached.
- ◆ Due to the beam current of damping ring is low enough, SEY of aluminium vacuum chamber which do not need NEG coating or TiN coating could meet the requirement of physics.
- ◆ RF shielding Bellows with spring and contact fingers made of stainless steel will be employed to absorb the extension and the misalignment of vacuum chambers and other vacuum devices during installation.

Prototypes of Dump chamber and membrane window

- ◆ The elliptical Ti thin membrane window of 170×10 mm with a thickness of 0.1 mm was welded on the s. s. plate with a diameter of 183 mm and a thickness of 5mm.



◆ Membrane windows

- The thickness of Ti window is 0.1mm
- Deformation test under vacuum: elliptical window is 0.4mm, circle window is 2.3mm;
- ultimate vacuum $< 5 \times 10^{-10}$ Torr.

CEPC vacuum chamber production line

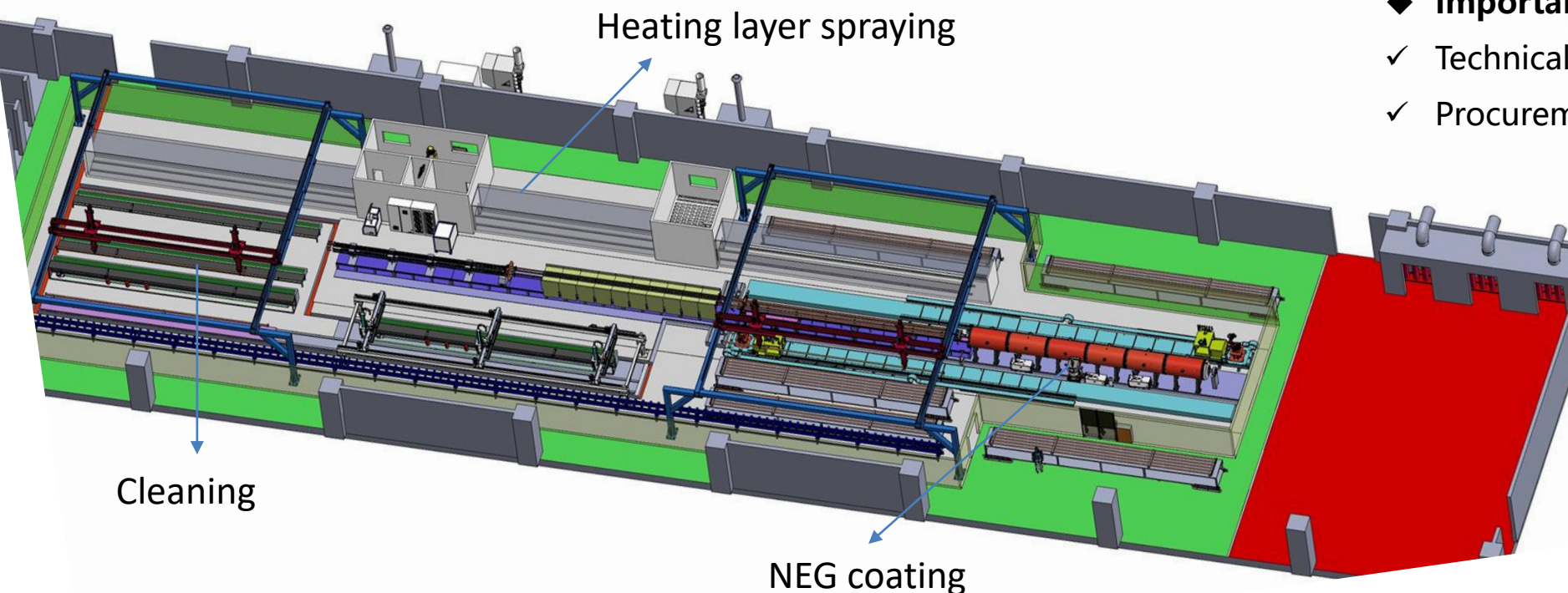


■ Requirement

- Due to the difference in length, two production lines will be used to complete the production of vacuum chambers for the CEPC collider. The quantity of NEG coating and spraying facilities for the two lines varies to match the production speed.
- With two production lines, the all vacuum chambers of collider will be finished in 5 years.

■ Advantages

More stable process, less manpower, less NEG coating facility, more adaptive capacity in production, etc.



◆ Important nodes and progress

- ✓ Technical scheme review 2024.10
- ✓ Procurement bidding 2024.12

Items	Specifications
Dimension	• L 11400-d56-D62
Weight	• 50~100kg
NEG coating	• Thickness: 200nm ± 30% • SEY < 1.1 • S、Q、 life-times
Spraying heating	• Thickness < 0.5mm • Heating temperature < 300°C

Production line composition



Classification	Sub-devices	Parameters	Note
Electron-beam welder	<ul style="list-style-type: none"> • Electron-beam gun • Power supply • Vacuum chamber 	<ul style="list-style-type: none"> • Meets the Length of 11.4m vacuum chamber • 6 working position 	Design and manufacturing
Brazing	<ul style="list-style-type: none"> • Mechanical holder • Power supply 	<ul style="list-style-type: none"> • 350°C • 11.4m long 	Low temperature brazing in air by conductivity heating, expecting steady by double hole copper tube
Heating film spraying facility	<ul style="list-style-type: none"> • Electron-beam gun • Power supply • Controller • Mechanical Structure 	<ul style="list-style-type: none"> • Meets the Length of 11.4m vacuum chamber • Multilayer Spray • Ceramic and conductivity layer 	R&D
NEG coating tower	<ul style="list-style-type: none"> • Pumping system • Vacuum measurement • Power supply • Vacuum chambers • Discharge Gas • Cathode、controller 	<ul style="list-style-type: none"> • Meets the Length of 11.4m vacuum chamber • 6 working position • Background vacuum <math>5 \times 10^{-7}</math>Pa • Baking temperature 200°C 	Developing to be more fitted the production line
Measurement and testing	<ul style="list-style-type: none"> • Dimension measurement • Leakage testing 	<ul style="list-style-type: none"> • Dimension measurement 11.5m/0.1mm • Leakage testing 1×10^{-10} mbar·L/s 	Design and manufacturing
Cleaning	<ul style="list-style-type: none"> • rinsing 	<ul style="list-style-type: none"> • deionized water rinsing 	Design and manufacturing
Production line auxiliary equipment	<ul style="list-style-type: none"> • Moving band • robot arm system • controller 	<ul style="list-style-type: none"> • Meets the Length of 11.4m vacuum chamber 	Design and manufacturing

Procedure of NEG coating, spraying

■ Spraying

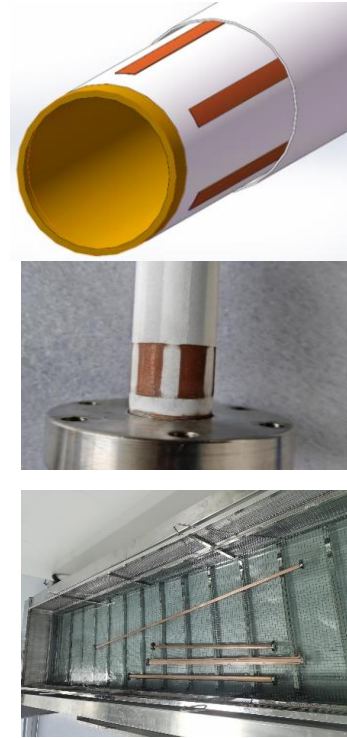
- Sandblasting
- Spraying_Isolation_layer
- Spraying_Conductivity-layer
- Spraying_Isolation-layer
- Spraying_Contactor-layer

■ Cleaning

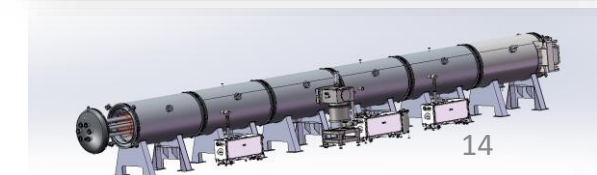
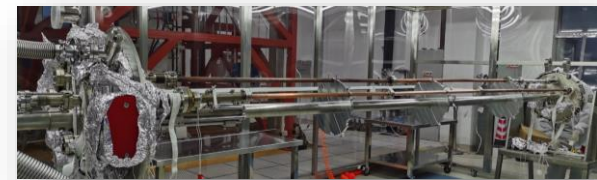
- Outside
- Inside

■ NEG coating

- vacuum chambers, cathodes assembling by mechanical arms (flanges sealing).
- Leakage testing.
- Deliver the assembles to vacuum oven/ baking/ NEG coating;
- Disassembly the vacuum chambers

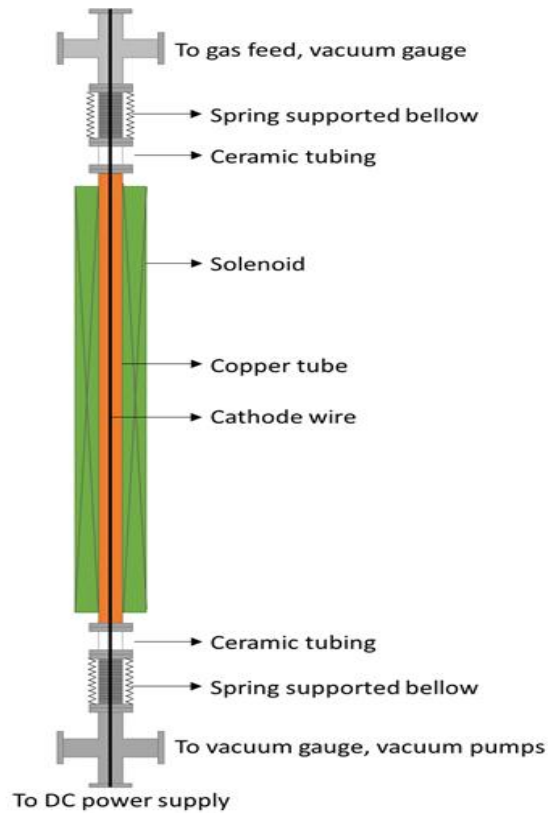


Function	Materials	Thichness/um
Transition-layer	MCrAlY alloy	50~100
Isolation-layer	Al2O3 cermic	~150
Conductivity-layer	NiCr alloy	~100~200
Isolation-layer	Al2O3 cermic	~150
Contactor-layer	Copper	~50



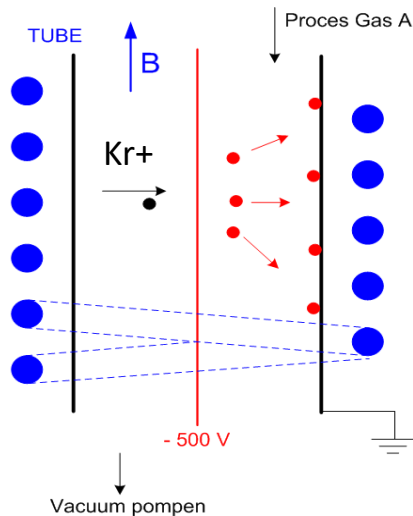
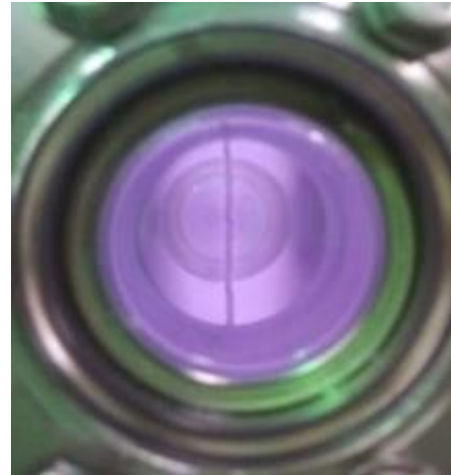
NEG coating mechanism & method

- HEPS, LHC, MAX IV, SIRIUS, APS_U etc.

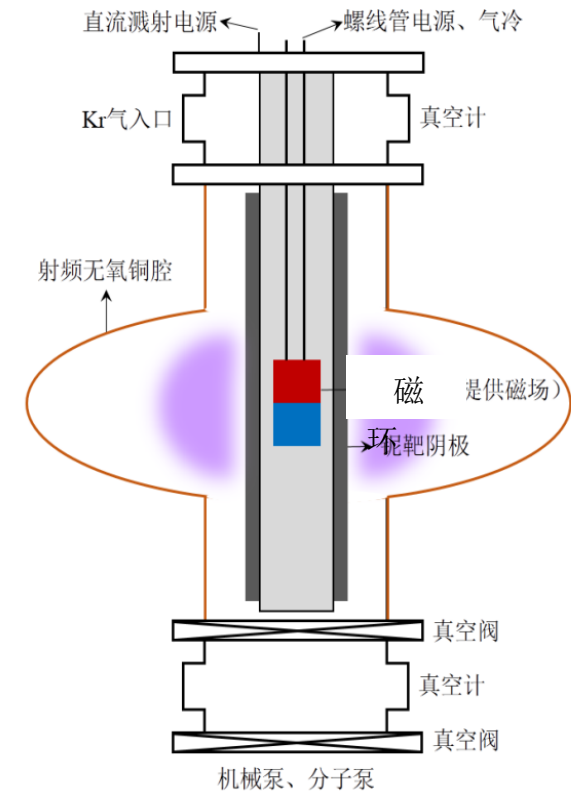


Outside magnet (solenoid)

Cathode wire



- CSNS, BEPCII vacuum chambers;
- Nb coating;

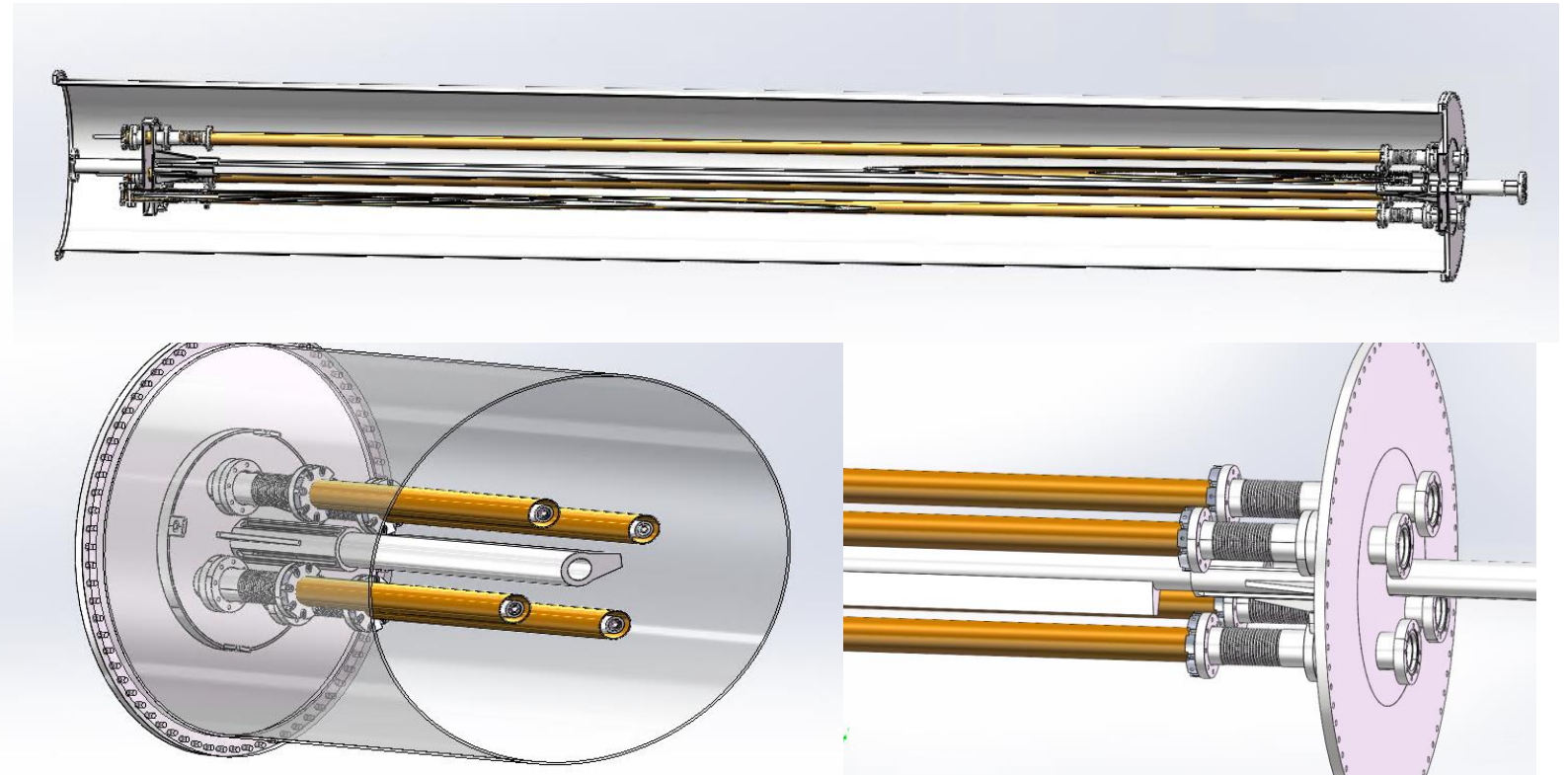
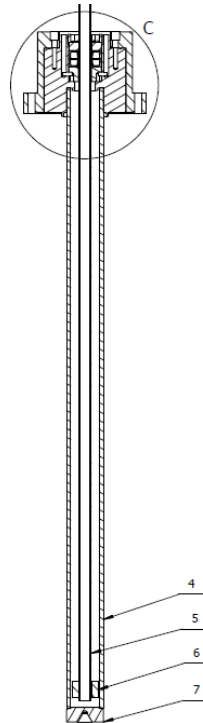


Inside magnet

Magnetron sputtering cathode

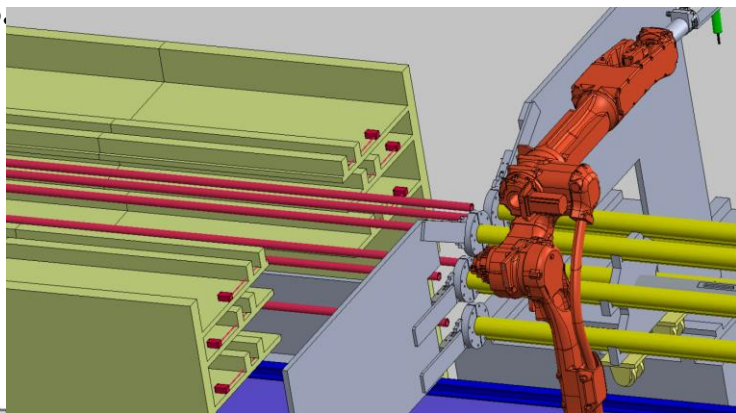
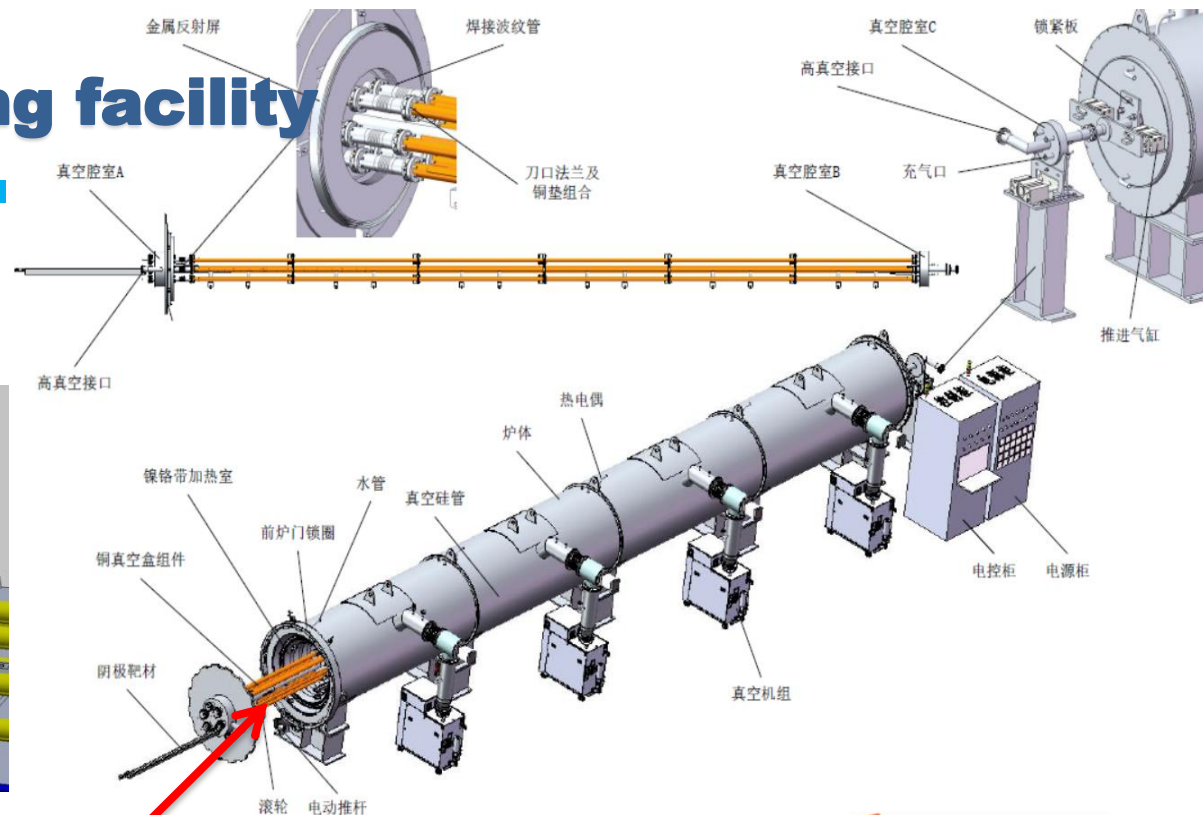
Massive production of NEG coating for CEPC—Upgrade plan

- Due to the diameter of CEPC is D56, we plan to replace the cathode wire with a magnetron sputtering cathode
- Permanent magnet instead of the solenoid which supplies magnetic field for DCMS;
- By combining the low vacuum chamber outside of the vacuum chambers to be coated with NEG, the high vacuum process is simplified;

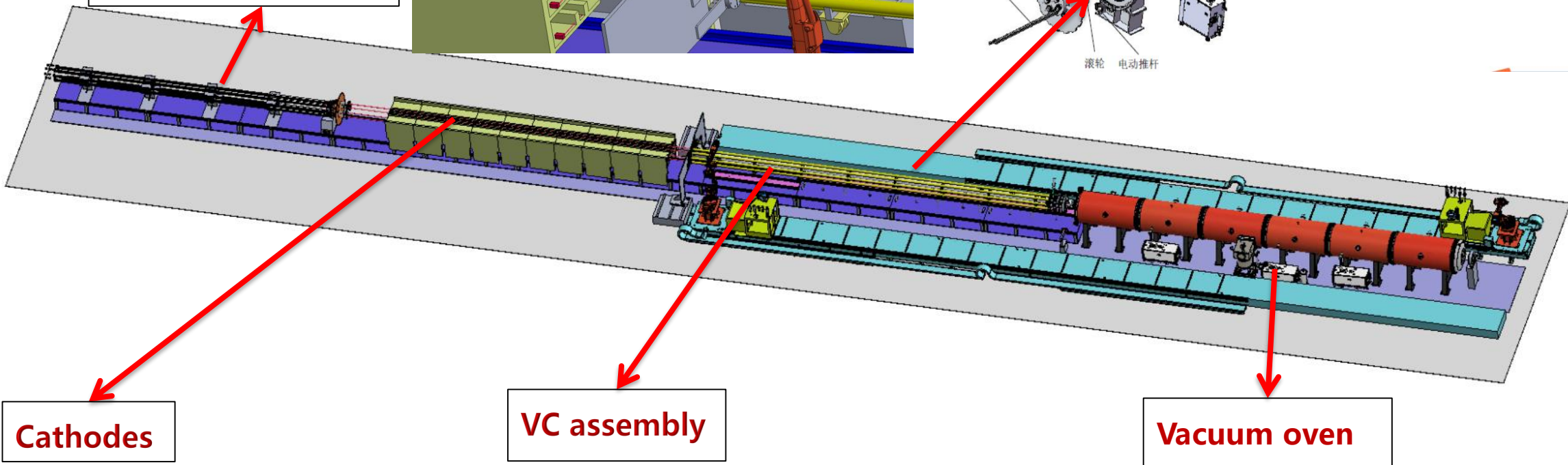


layout & composition of NEG coating facility

- NEG coating, VC assembly and disassembly with automatic robot arms.



Cathodes driven

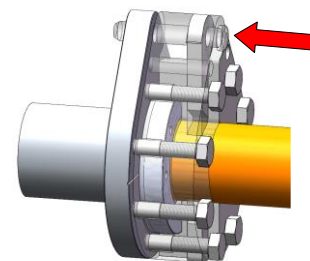
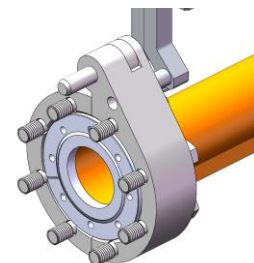
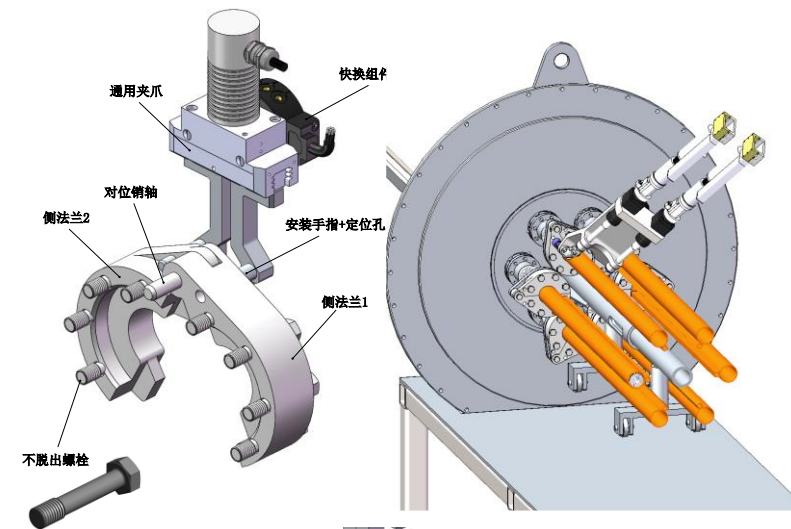
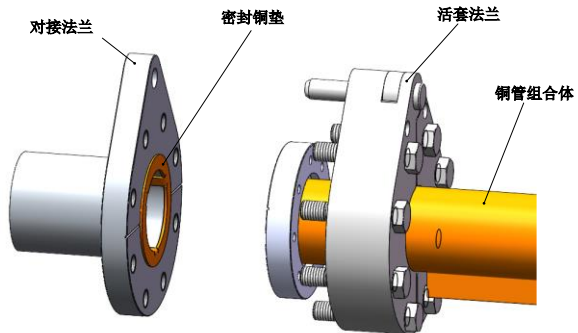
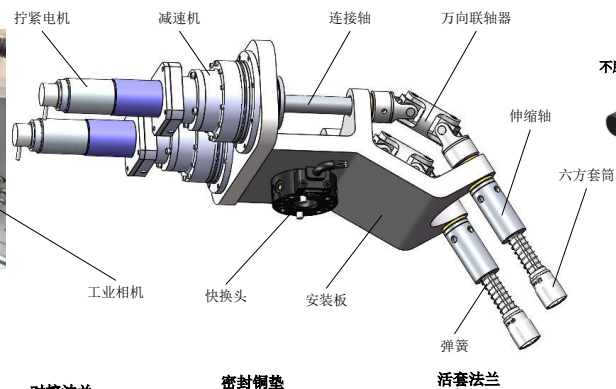
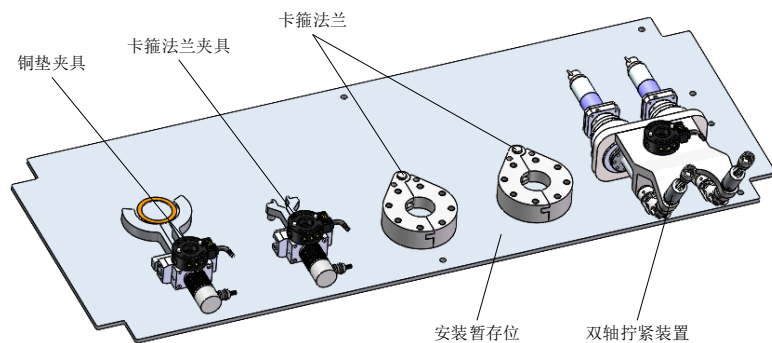
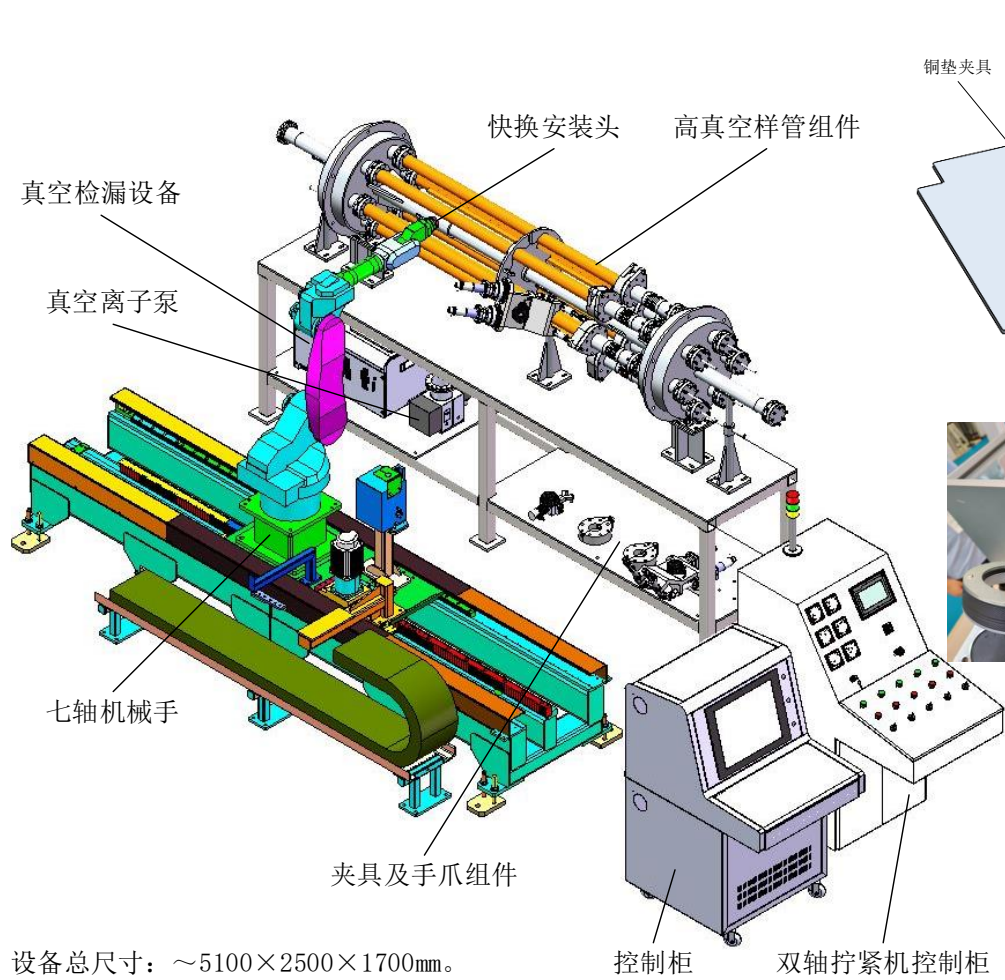


Cathodes

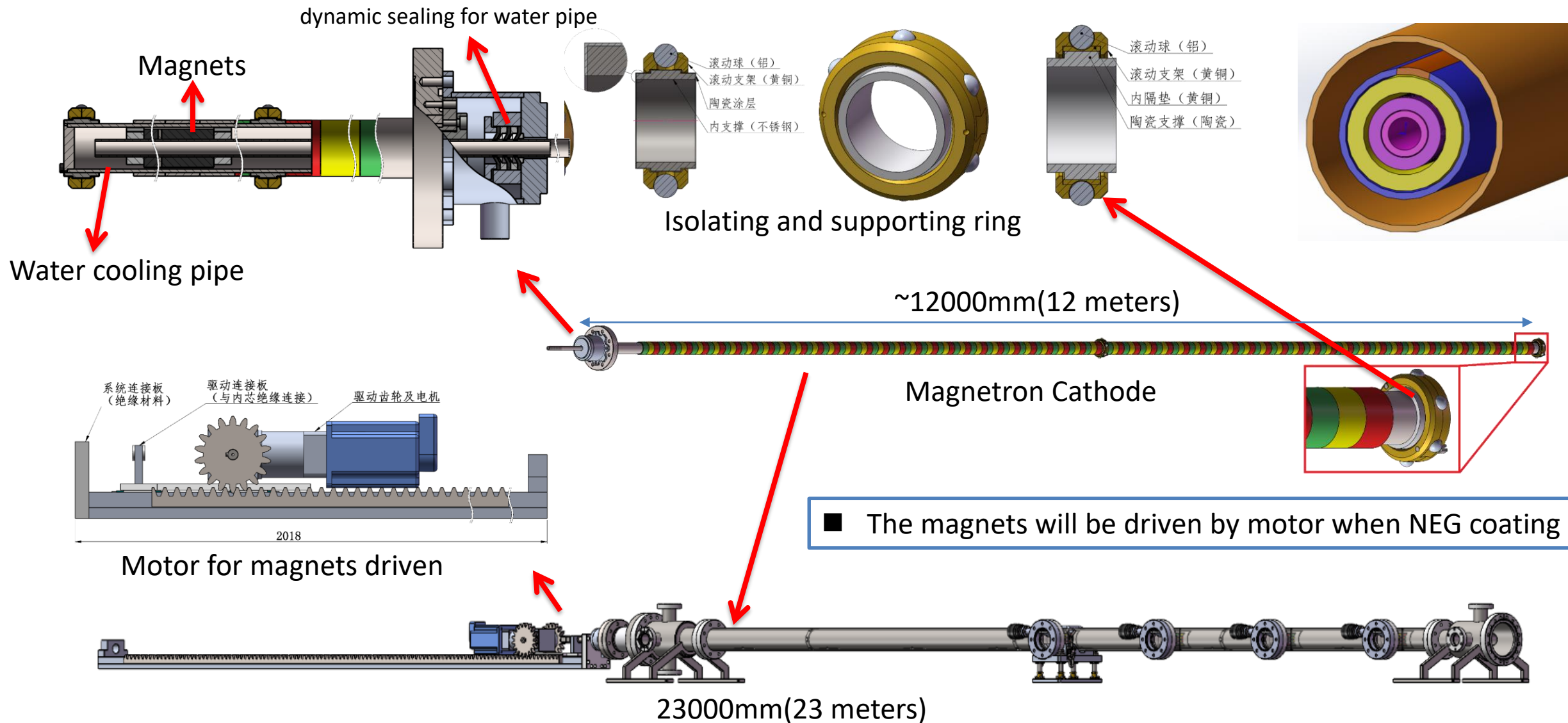
VC assembly

Vacuum oven

Prototype of vacuum chambers assembly



Prototype of cathode for NEG coating



VC baking & Why spray heating film

The baking is the most crucial procedure in achieving ultra-high vacuum

❑ Necessity:

- ✓ In order to meet the ultra-high vacuum requirement of achieving a dynamic vacuum level of 3.0E-10 mbar.
- ✓ NEG coating reactivation

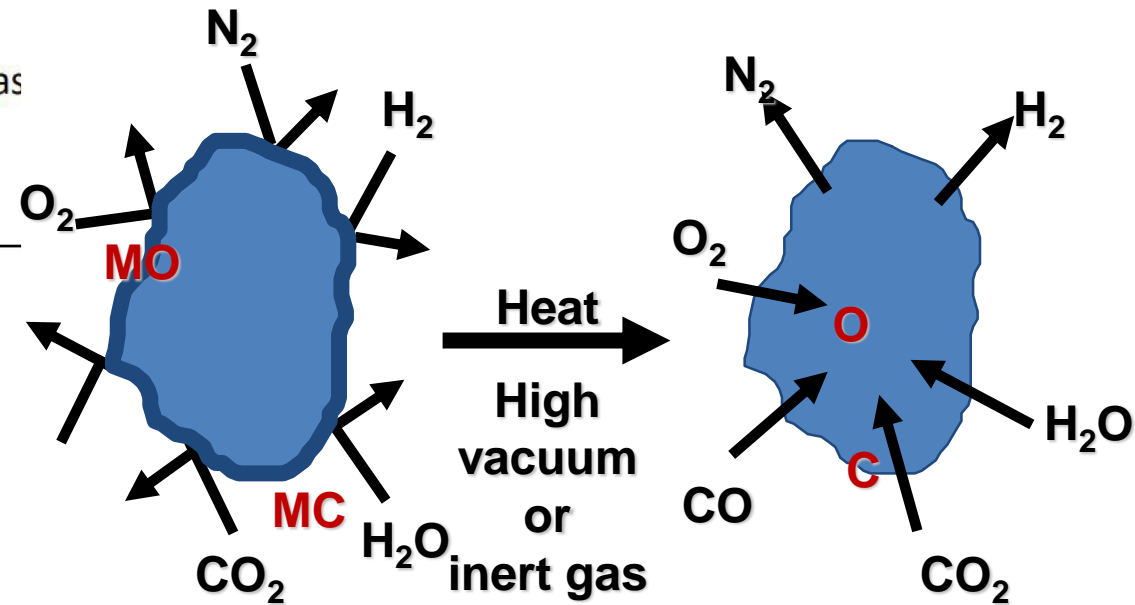
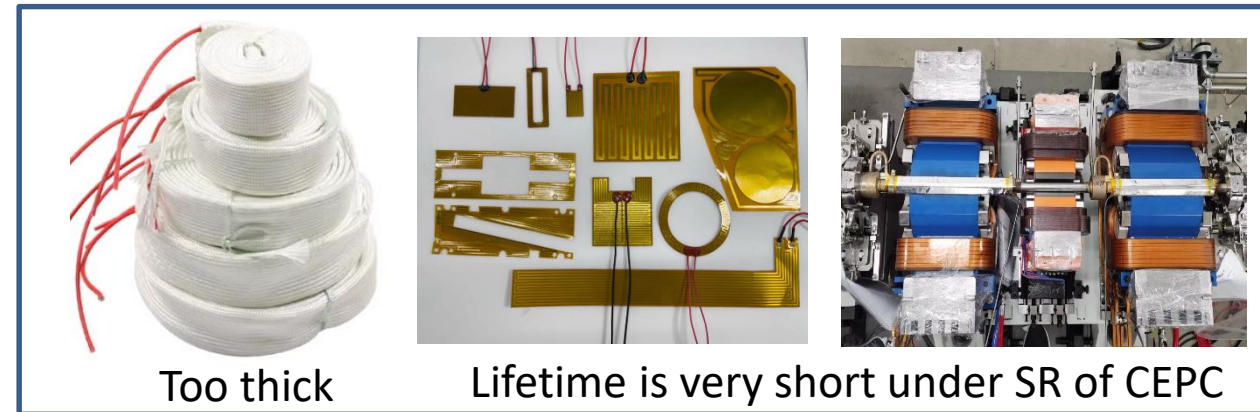
For metals:

- If not baked (not heated) in-situ **water** is the dominant gas specie.
- If baked (heated above ~120°C) in-situ **hydrogen** H₂ is the dominant gas

$$q_{H_2O} \approx \frac{3 \times 10^{-9} \text{ [mbar l]}}{t[h]} \text{ [s cm}^2\text{]}$$

Outgassing rates $q \text{ [} \frac{\text{torr l}}{\text{s cm}^2}\text{]}$ at 20°C:

Austenitic stainless steel not baked, after 10 h pumping	3×10^{-10} (main gas: H ₂ O)
Austenitic stainless steel baked in-situ for 24 h at 150°C	2×10^{-12} (main gas: H ₂)
OFS copper baked in-situ for 24 h at 200°C	$\sim 10^{-14}$ (main gas: H ₂)



Spraying for heating film

- ◆ Multilayer heating film will be coated outside of the vacuum chamber which composed by ceramic and conductivity layer
- ◆ The heating temperature could reach 250°C

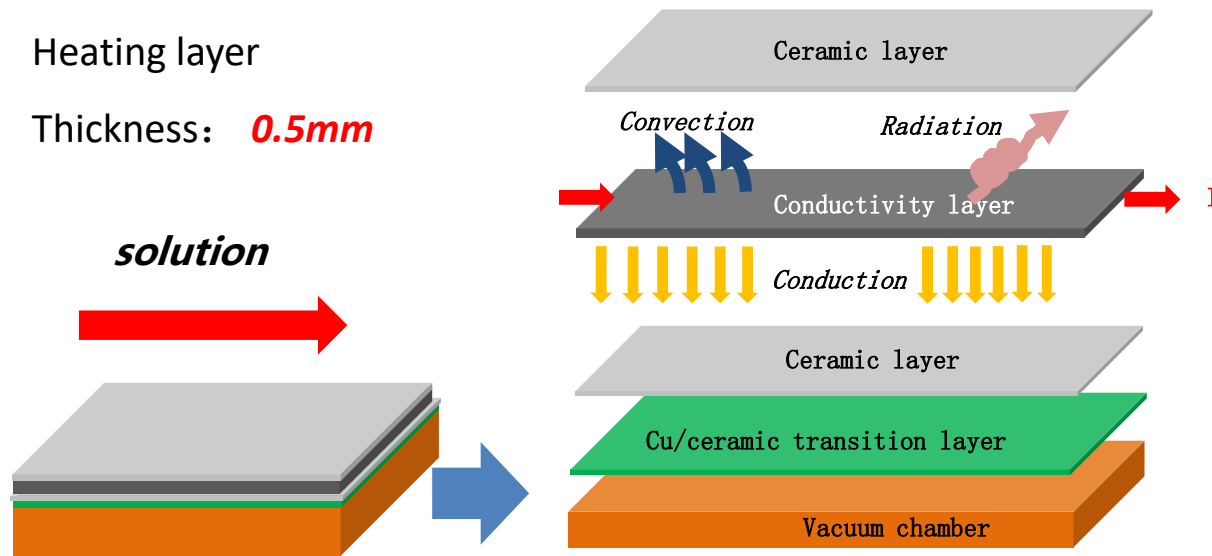
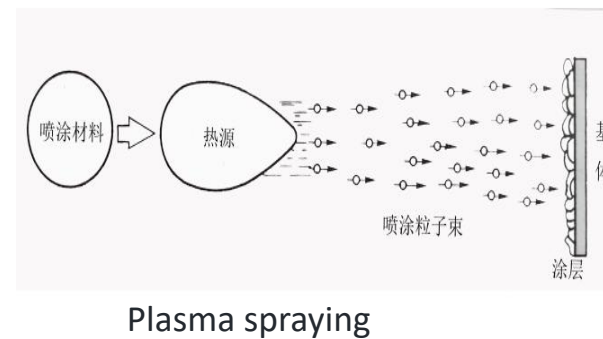
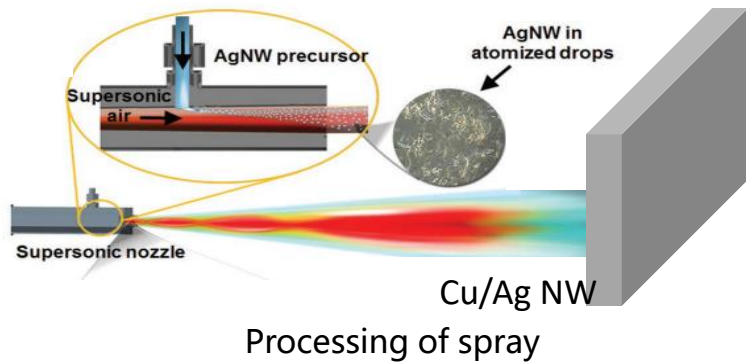
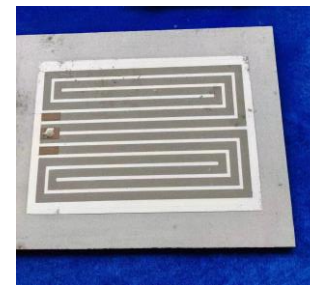


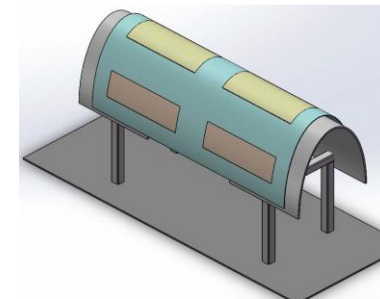
图 2.4 Oerlikon Metco UniCoatPro 大气等离子喷涂设备: (a)控制部分; (b)喷涂部分



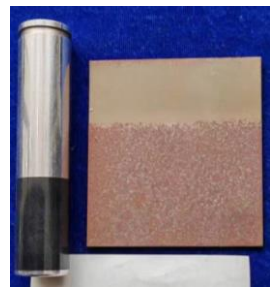
■ Related commercial products



Electric heating circuit



De-icing for airplane

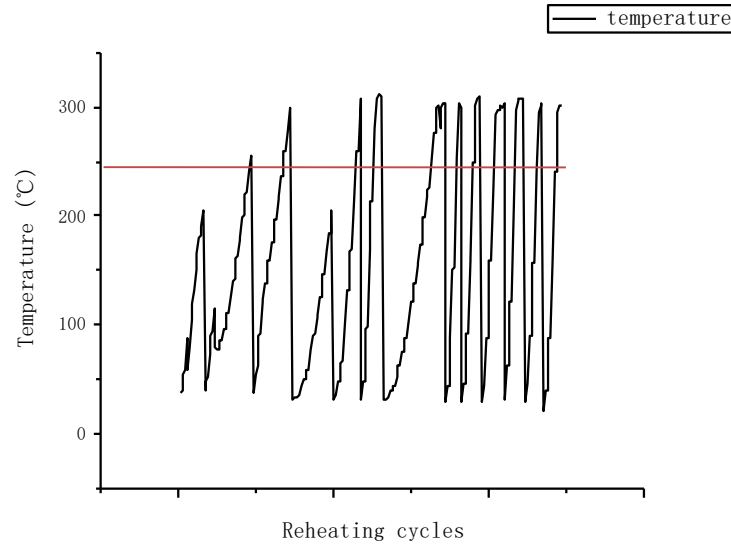


Spraying for heating film

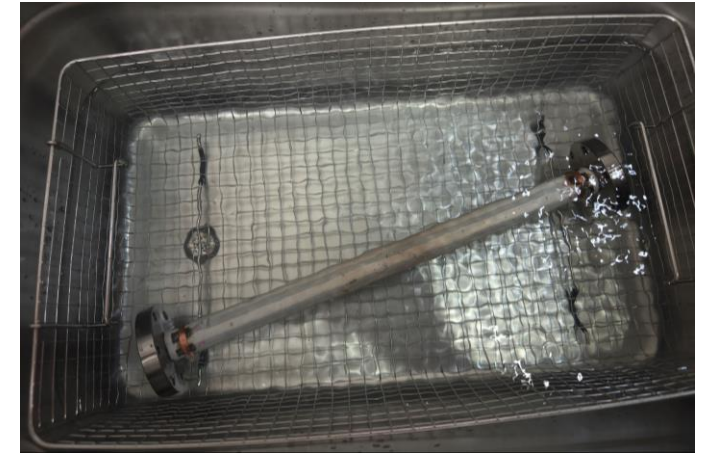


Prototype of Spraying heating film and tests

Reheating test more than 12 times



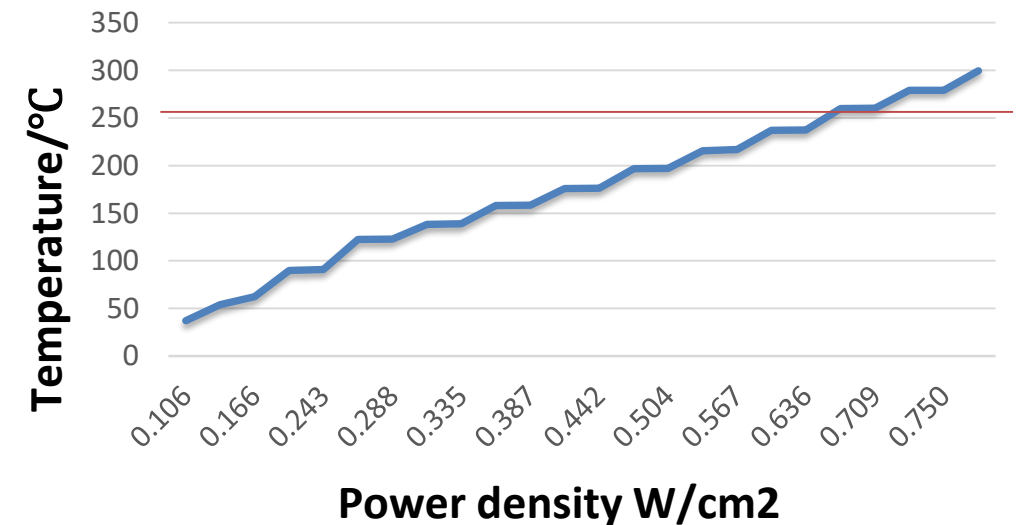
Adhesion test in ultrasonic resin



Dimension: L400*D24 Substrate: copper

Function	Materials	Thickness/um
Transition-layer	MCrAlY alloy	50~100
Isolation-layer	Al2O3 ceramic	~150
Conductivity-layer	NiCr alloy	~100~200
Isolation-layer	Al2O3 ceramic	~150
Contacto-layer	Copper	~50

Temperature vs Heating Power



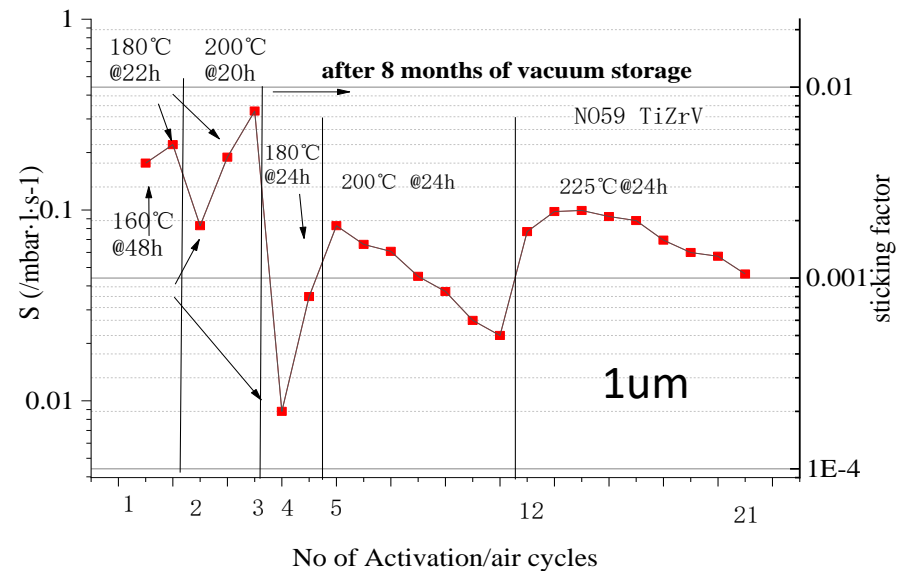
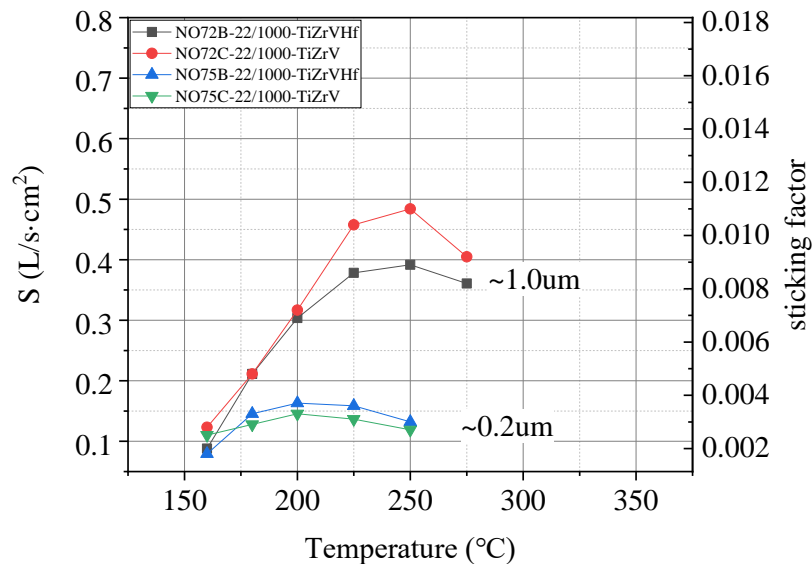
NEG coating optimization in EDR

Impedance

Round pipe of Copper (2~3mm) with NEG coating (200nm)

Strictly control on the coating thickness for impedance source to restrain the instability! 【1】

Reactivation life-times

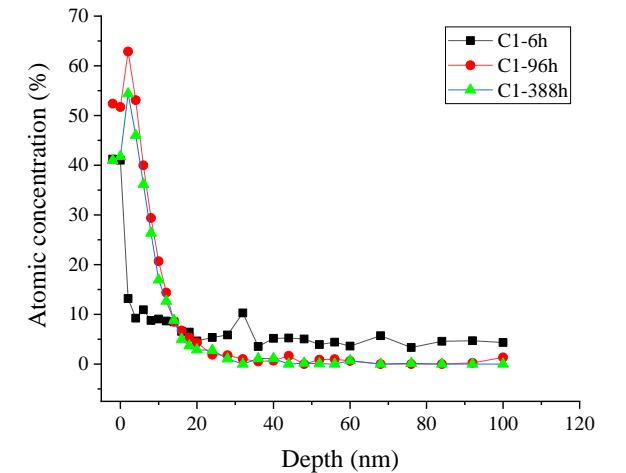
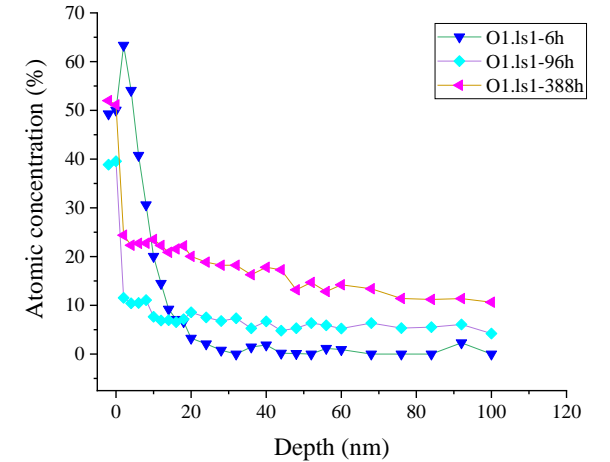
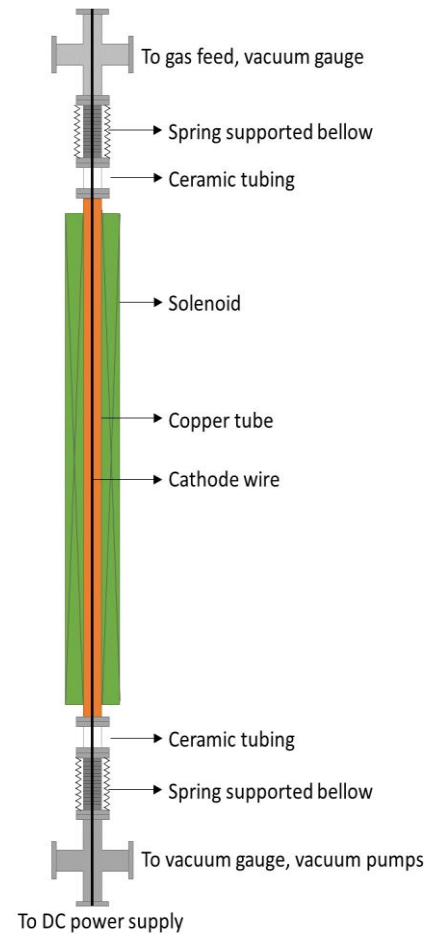
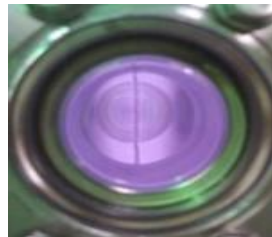
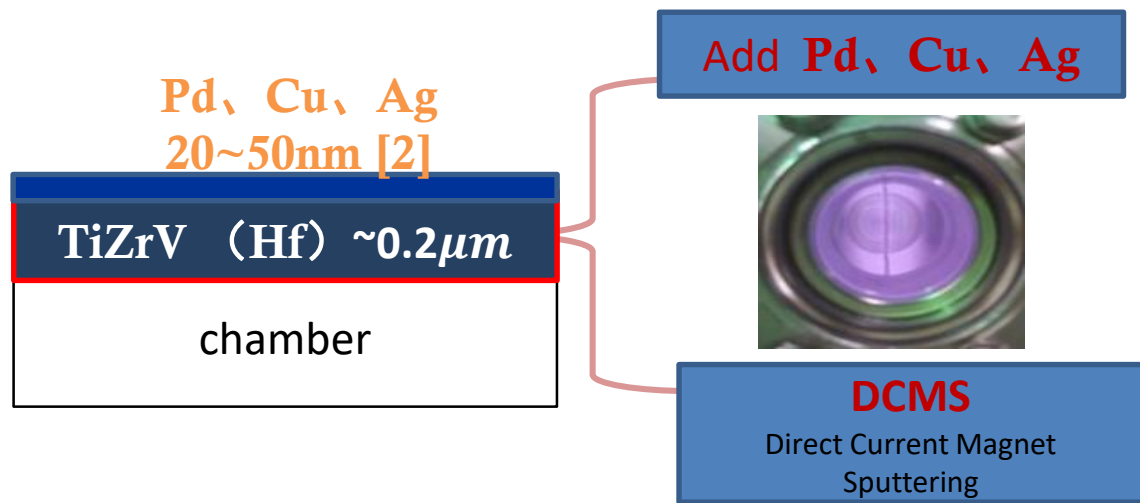


Problems: 200nm NEG coating, pumping performance (pumping speed and life) rapidly decreased

NEG coating optimization _ Next step

- Multilayer NEG coating: improve lifetimes, conductivity.

The application of a thin palladium (Pd) layer to a getter film has been proposed as a means of preventing oxidation of the getter layer so as to address the issue of limited operational lifespans.[1]

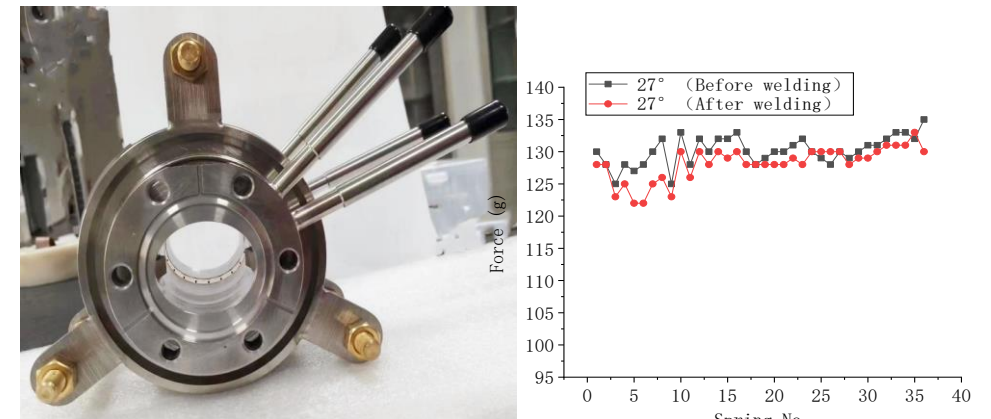
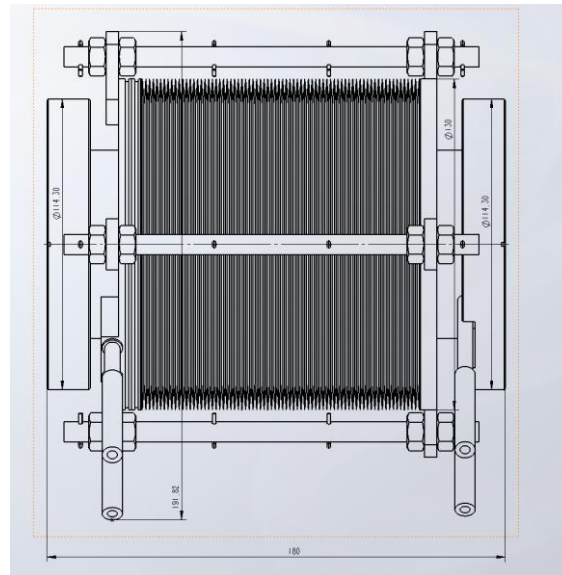
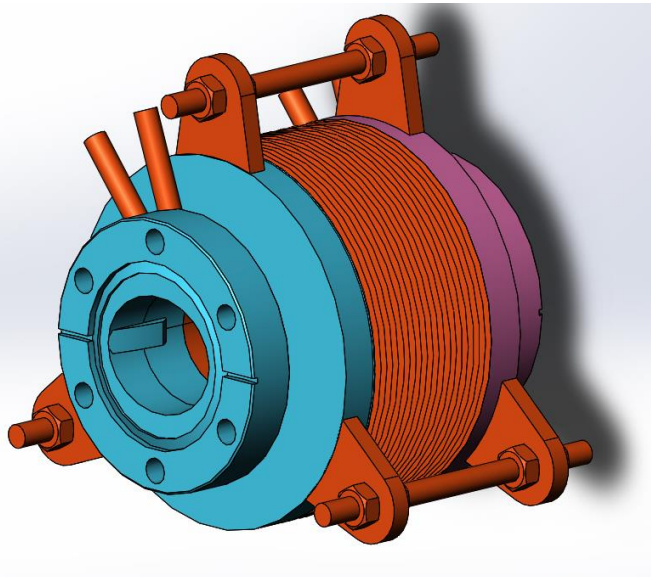


[1] C. Benvenuti, P. Chiggiato, F. Cicoira, Y. L'Aminot, V. Ruzinov, Vacuum properties of pallium thin film coatings, Vacuum 73 (2004) 139–144.

[2] JIN X, TANIMOTO Y, UCHIYAMA T, et al. Synchrotron radiation-stimulated desorption from Pd or Pd/TiZrV coated copper tubes [J]. Vacuum, 2021, 192(110445).

Full-scaled size RF shielding bellows development

- RF shielding Bellows for ultra Expansion/contraction: Ultra Expansion/contraction RF bellows to meet the 11.5m long vacuum chambers.
- Mask is designed on the upstream of RF bellows to absorb the SR
- The all RF bellows were produced by local company in China, and massive used in HEPS.



Conclusion

- Vacuum chambers with Al, Copper alloy materials have been conducted in BEPC II, HEPS, and also NEG coating have been applied in HEPS with thickness of 1 μm , For CEPC, 0.2 μm NEG coating is a crucial technology, due to its short time life-cycles.
- Production line of vacuum chambers NEG coating and spraying heating will be R&D in 2 years;
- ✓ NEG coating by magnetron sputtering cathode method R&D will be carried out to adapt the production line;
- ✓ Prototype of Spraying heating film and tests have been carried out, which shows a good result;
- NEG coating optimization for low impedance film, Spraying for heating film plan to be carried out ;

Acknowledgement

- A significant amount of work has been completed in the CDR and TDR, and I would like to thank all those who have contributed to these efforts.
- Thanks for the HEPS, FCC-ee project;

Thanks for your attention